



CLEANROOM WET CHEMISTRY

RCA Cleaning Bench

Pre furnace cleaning of Silicon (Si) substrates

- Heated quartz tanks for SC1 & SC2 solution
- HF/BOE dip Tank
- 2 Quick Dump rinsers w/ N₂ sparging



Metal etch/BOE Bench

Resistance evaporator for thin metal films

- Left Side for Metal and Si Etching
- Right side for BOE only
- Tooling for single sided etching



Large Substrate Bench

Manual cleaning bench for up to 12 inch wafers

- 2 Heated PTFE Tanks for SC1 & SC2
- 2 PVDF Tanks for HF/BOE & Spill over Rinse
- Built in Glove Washer

